

Docket No. AM1562D1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

YIQIONG WANG

Confirmation No. 8856

Serial No.: 09/882,141

Examiner: Umez-Eronini

Filed: June 15, 2001

Group Art Unit: 1765

For: METHOD OF ETCHING HIGH ASPECT  
RATIO OPENINGS IN SILICONRESPONSE UNDER 37 CFR 1.115To: Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

In response to the office action of February 25, 2003,  
please amend the above-identified application as follows.